

Sheet 1 of 2

US Patent No. 1449 (REV. 1/06)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 125473	APPLICATION NO. 10/551,130
	INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)		
	APPLICANT Takahiro KISHIOKA		
FILING DATE September 29, 2005		GROUP 1756	

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Examiner Initials	Cite No.	Document Number	Date	Name
CH	1	US 5,919,599	7/6/1999	Meador et al.
CH	2	US 5,693,691	12/2/1997	Flaim et al.
CH	3	US 6,114,085	9/5/2000	Padmanaban et al.
CH	4	US 6,388,039 B1	5/14/2002	Jung et al.
CH	5	US 6,492,092 B1	12/10/2002	Foster et al.
CH	6	US 2002/0093069 A1	7/18/2002	Hong et al.
CH	7	US 2002/0127789 A1	9/12/2002	Hong et al.
CH	8	US 2002/0009595 A1	1/24/2002	Hong et al.

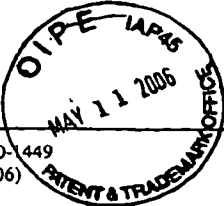
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CH	10	JP A 2002-47430	2/12/2002	Japan	X	X
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CH	24	JP A 10-120939	5/12/1998	Japan	X	X
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Sheet 2 of 2

Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 125473	APPLICATION NO. 10/551,130
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OTHER DOCUMENTS				
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)		
CH	26	Lynch et al.; "Properties and Performance of Near UV Reflectivity Control Layers;" Proceedings of SPIE, 1994, Vol. 2195, pp. 225-229.		
CH	27	Taylor et al.; "Methacrylate Resists and Antireflective Coatings for 193 nm Lithography;" Proceedings of SPIE, March 1999, Vol. 3678, pp. 174-185.		
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EXAMINER	/Primary Examiner Cynthia Hamilton/			DATE CONSIDERED 09/21/2006
Examiner:	Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

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